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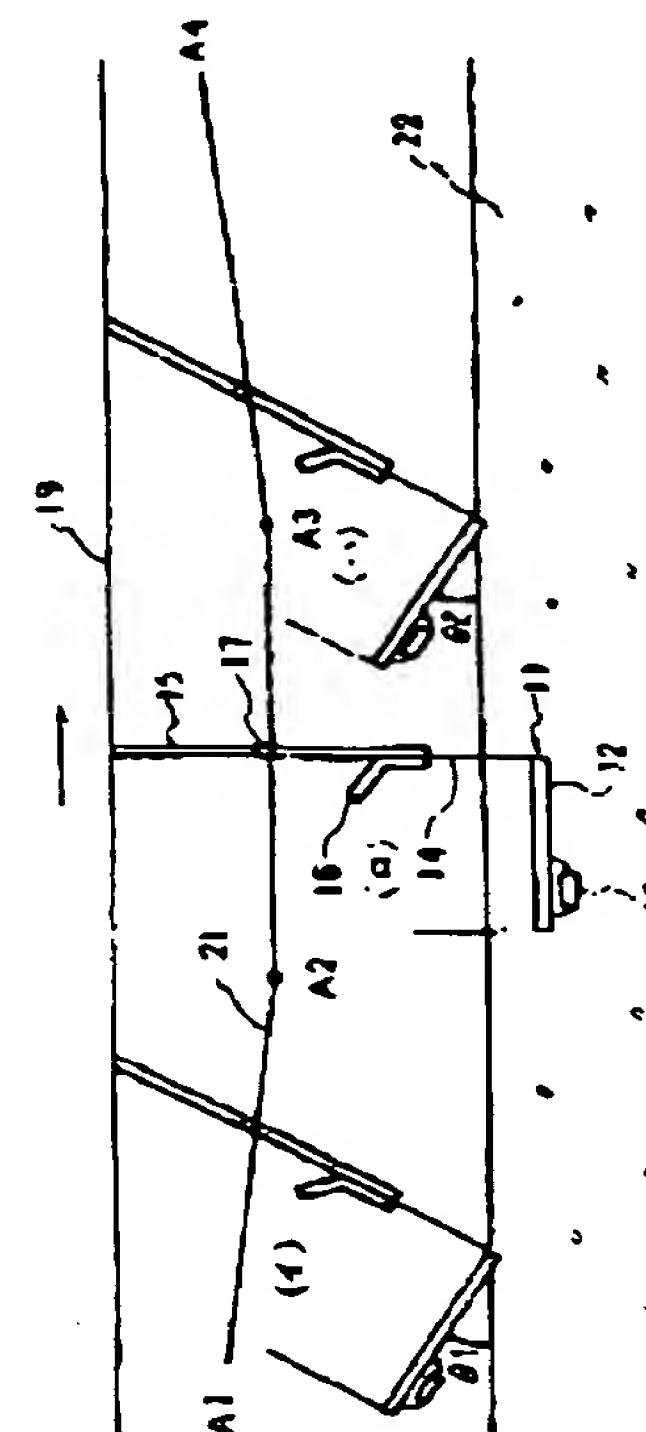
APPLICATION DATE : 13-07-83  
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INVENTOR : MIYAMOTO HIDETOSHI:

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TITLE : COATING APPARATUS FOR HYBRID  
 IC



ABSTRACT : PURPOSE: To uniform the thickness of a coating film and at the same time eliminate any air bubble by mounting a guide pin on a work holder, which pin is guided by a guide plate.

CONSTITUTION: A substrate 12 starts dipping at a carrying angle of  $\theta_1$  and the carrying angle is gradually made smaller until a guide pin 17 reaches a point A2, while the substrate 12 moves on in a coating liquid 22. When the pin 17 has reached the point A2, the substrate 12 becomes parallel to the liquid surface of the liquid 22. With this state retained, the substrate 12 continues to move in the liquid 22 until the pin 17 reaches a point A3. Thereafter, when the pin 17 has passed through the point A3, the substrate 12 moves on while making its carrying angle greater gradually and completely comes out from the liquid at the time when the carrying angle takes  $\theta_2$ . By thus adjusting the angles of the guide plate 21, it is possible to increase the carrying angles at the time of starting and terminating the dipping operation without deepening the dipping depth and further make the dipping time longer.

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